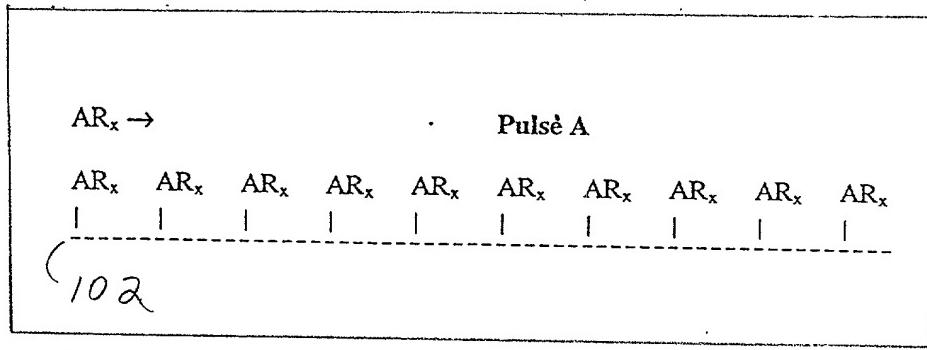


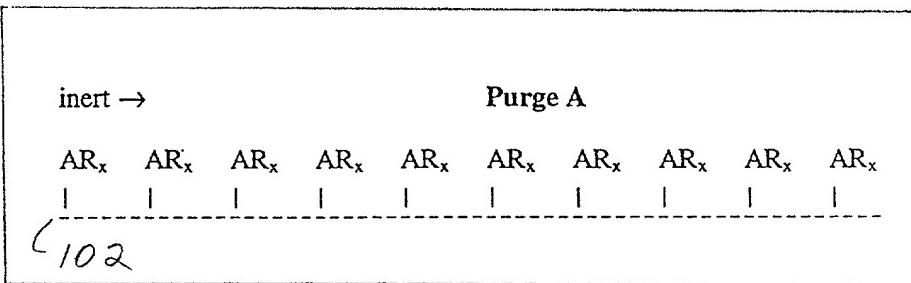
ATOMIC LAYER DEPOSITION SYSTEMS AND METHODS
OMSTEAD and LEVY
DOCKET NO. M-11953 US

1/8



↑
100

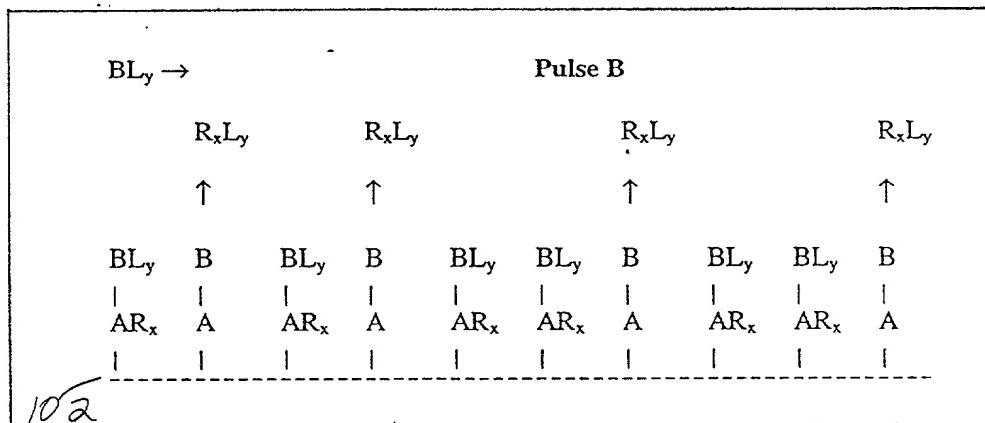
Fig. 1 (Prior Art)



↑
200

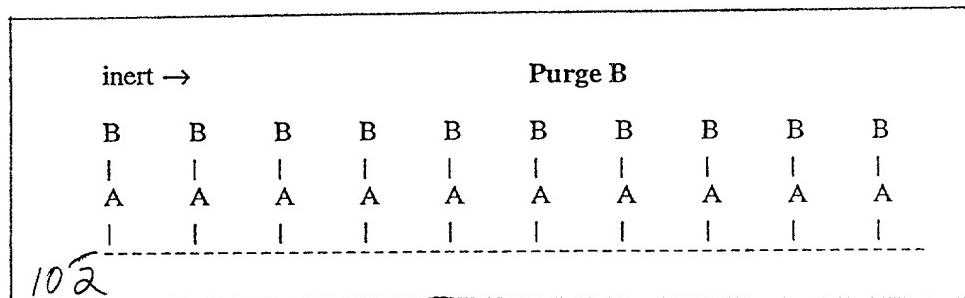
Fig. 2 (Prior Art)

2/8



↑
300

Fig. 3 (prior Art)



↑
400

Fig. 4 (prior Art)

3/8

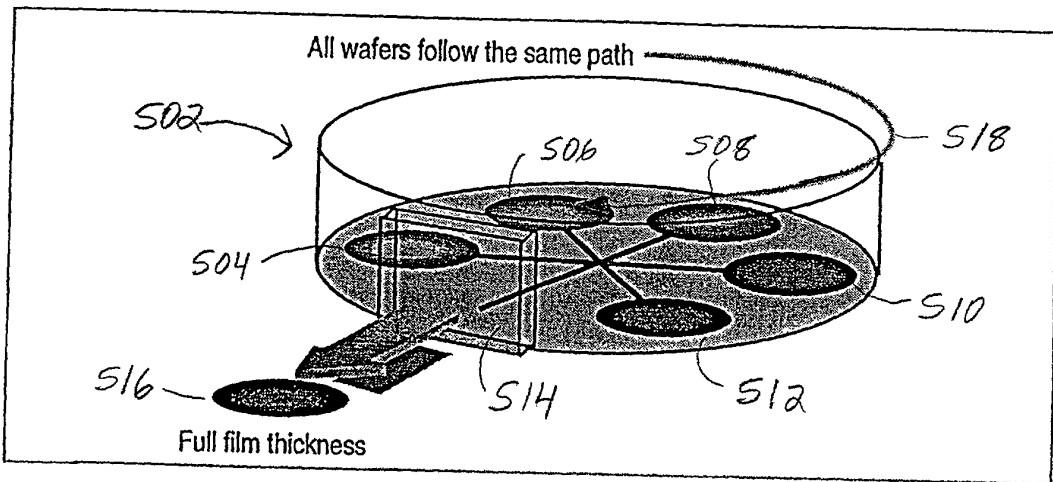


Fig. 5

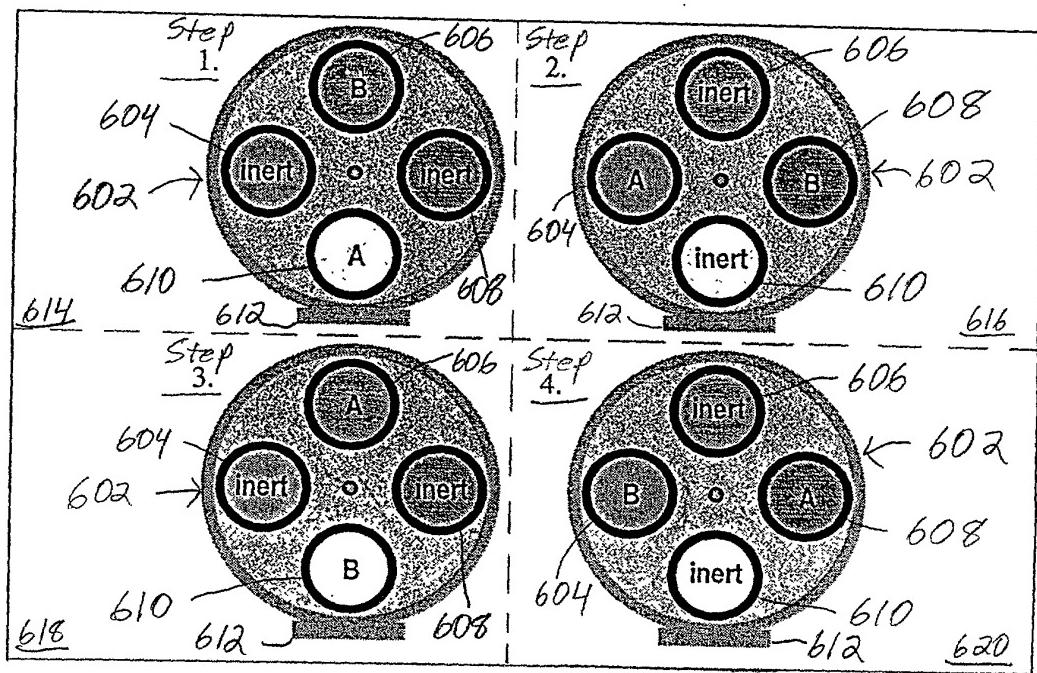


Fig. 6

4/8

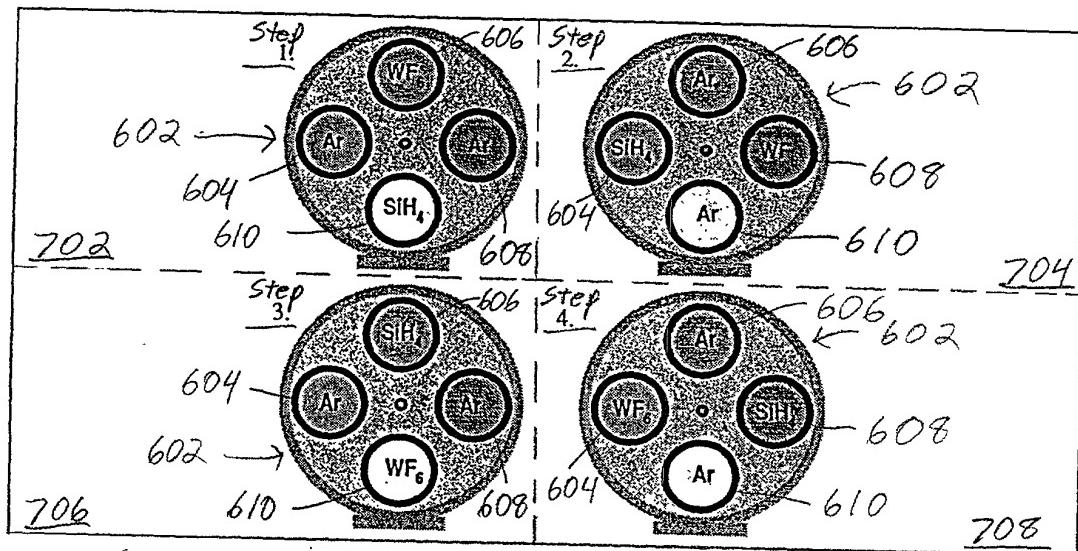


Fig. 7

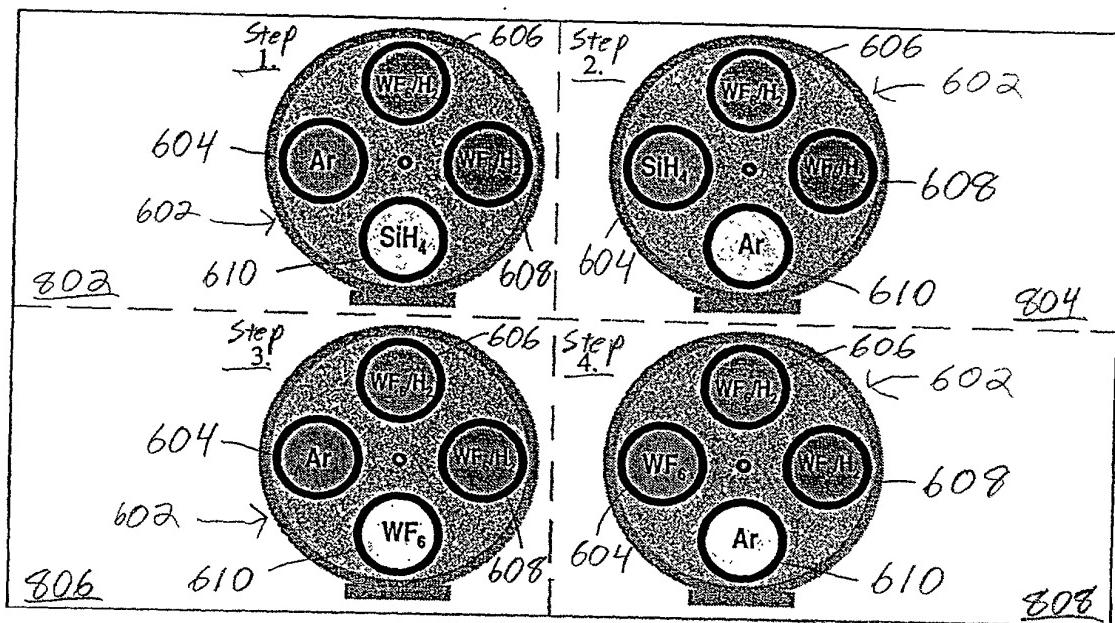


Fig. 8

5/8

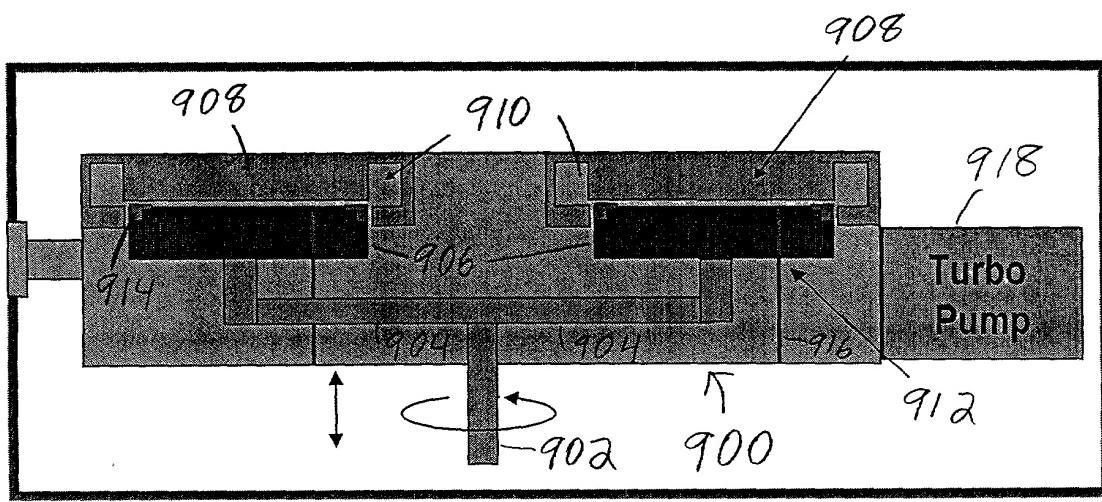


Fig. 9

6/8

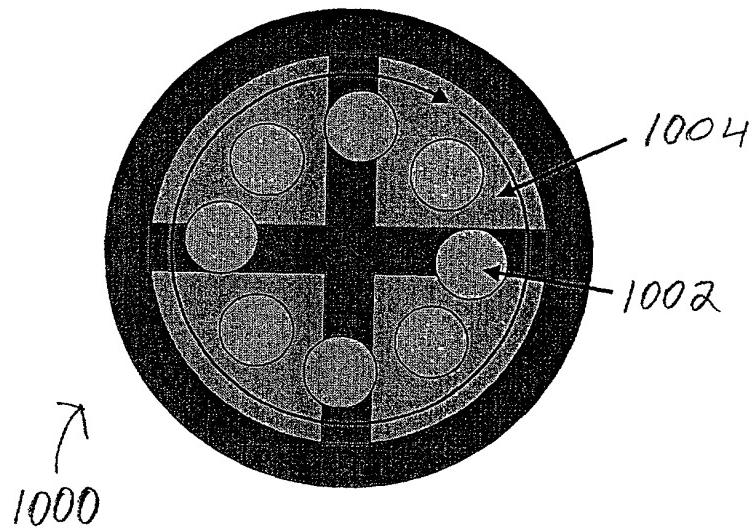


Fig. 10

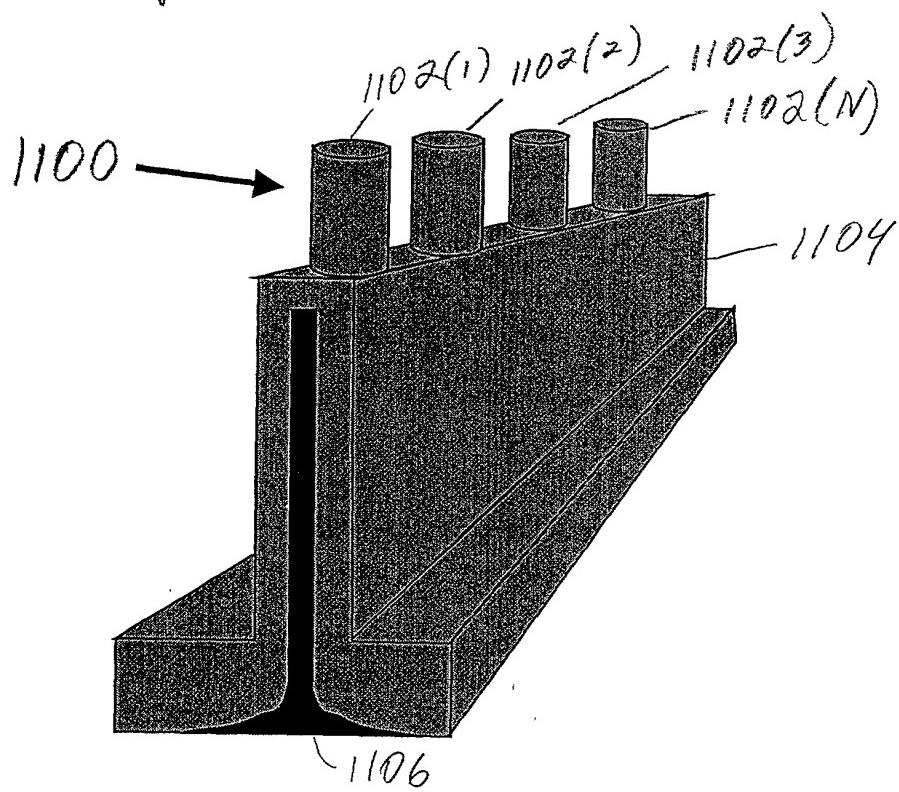


Fig. 11

7/8

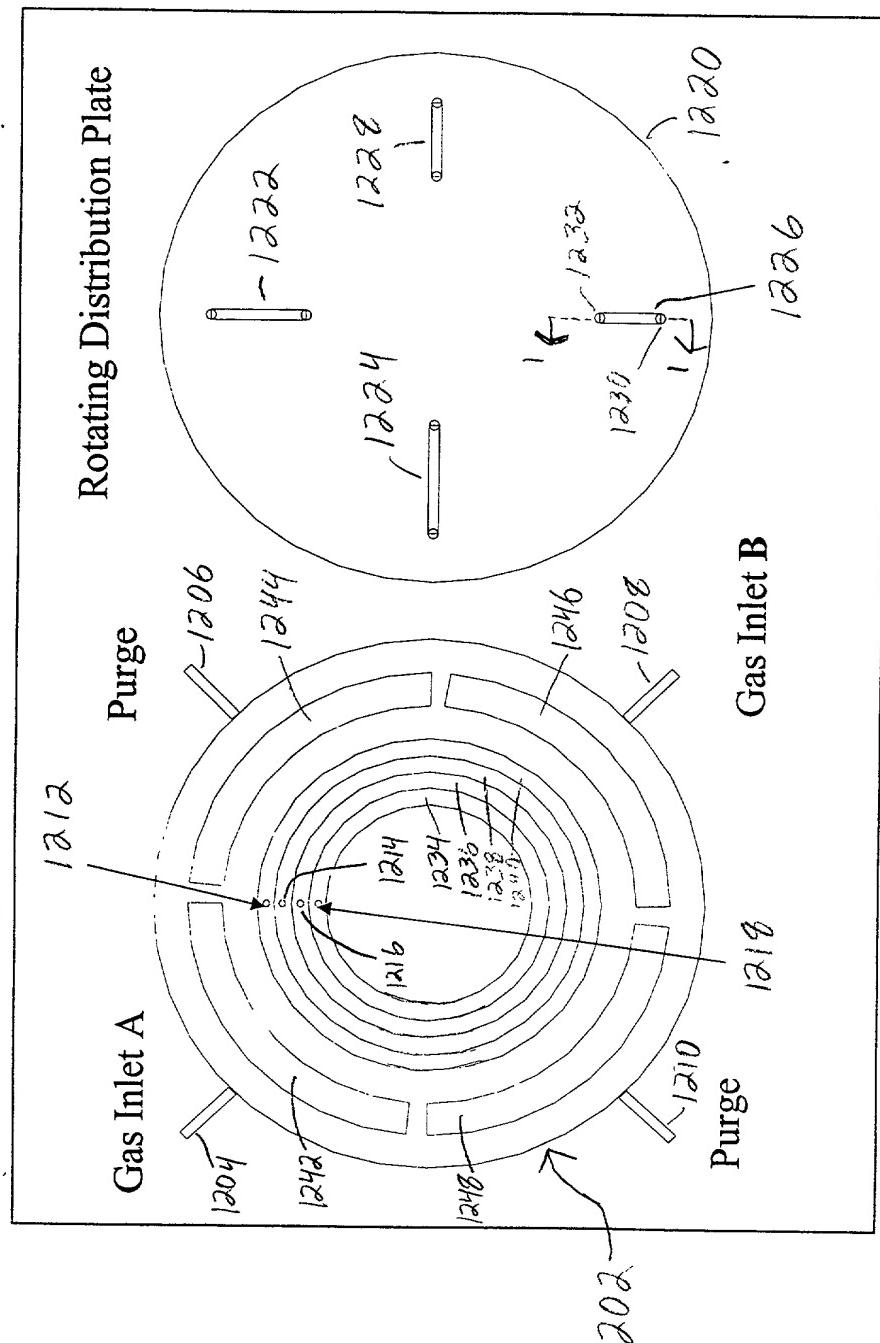


Fig. 12

8/8

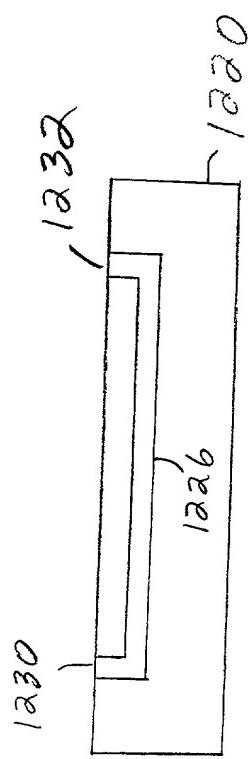


Fig. 13